FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. 58620.00010	SERIAL NO. 10/830,133 ~~New Application~~
LIST OF REFERENCES CITED BY APPLICANT	APPLICANT SBERVEGLIERI et al	
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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	AH								
	AI								
	AJ								
	AK								

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	AL	
	AM	
	AN	

EXAMINER	/John Fitzgerald/	DATE CONSIDERED	08/10/2007

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